



OK to enter  
my

AF  
IPW

**Response under 37 C.F.R. §1.116  
Expedited Procedure  
Group Art Unit 1712**

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

KOZAWA et al.

Attorney Docket No: 100021-00065

Application No. 10/005,347

Art Unit: 1712

Filed: December 7, 2001

Examiner: K. Peng

For: SILICON-CONTAINING POLYMER, PROCESS FOR ITS PRODUCTION,  
RESIST COMPOSITION EMPLOYING IT, PATTERN-FORMING METHOD AND  
ELECTRONIC DEVICE FABRICATION METHOD

**AMENDMENT AND RESPONSE UNDER 37 C.F.R. § 1.116**

**Mail Box AF**

Commissioner for Patents

P.O. Box 1450

Alexandria, VA 22313-1450

December 20, 2005

Sir:

This paper is filed in response to the final Office Action dated October 12, 2005, in connection with the above-identified application. Applicants respectfully request reconsideration and withdrawal of the rejections in view of the following amendments and remarks.

**Amendment to the claims begin at page 2.**

**The Remarks begin at page 4.**